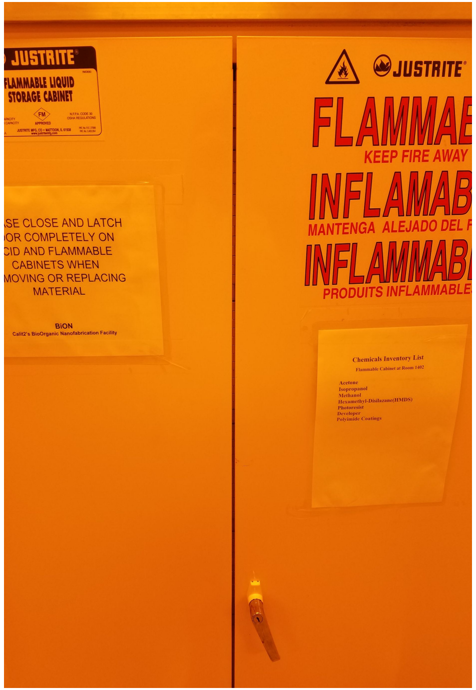
Safety Violations

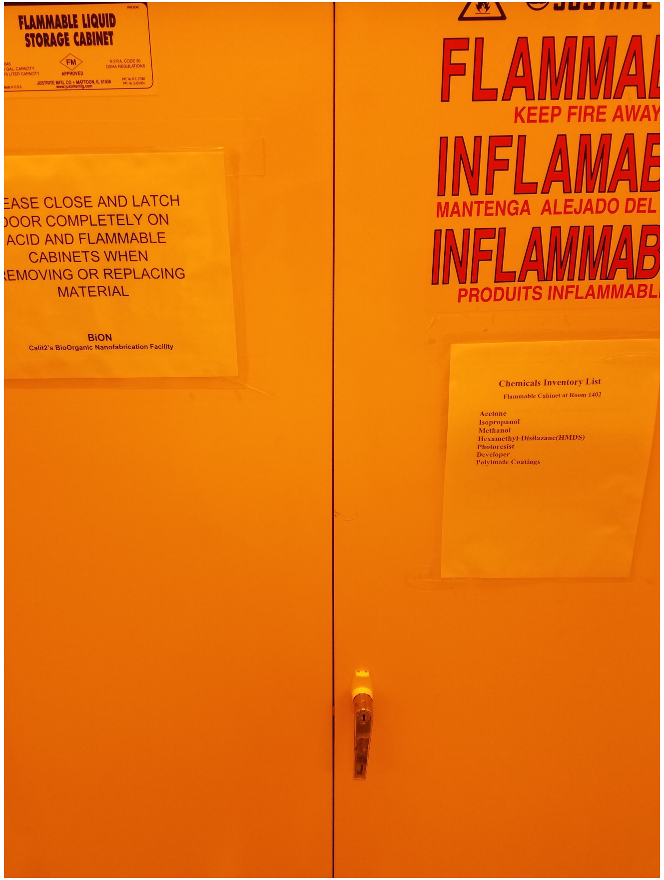
Common Examples

Frequently noticed violations

- Flammable cabinets not properly closed
- Illegible/Incomplete log books
- Hot Plates unattended and/or in forbidden areas
- Illegible/Incomplete process in progress and hazardous in use forms
- Microscopes lamps/lights left on
- Forged Sessions not started/stopped properly
- Trash left in the wrong trash bin
- Chemical bottles improperly stored
- Oven doors not closed properly, forbidden items found inside
- Lock Out / Tag Out tags not respected
- Chemicals left beyond their acceptable date
- Bulk chemicals not returned to flammable cabinets

- Flammable cabinets not properly closed






2314-2
SECURALL
Safety Storage Equipment
FLAMMABLE
KEEP FIRE AWAY
INFLAMABLE
MANTENGASE ALEJADO DEL FUEGO
INFLAMMABLE
GARDER LOIN DU FEU
PLEASE CLOSE AND LATCH DOOR COMPLETELY ON ACID AND FLAMMABLE CABINETS WHEN REMOVING OR REPLACING MATERIAL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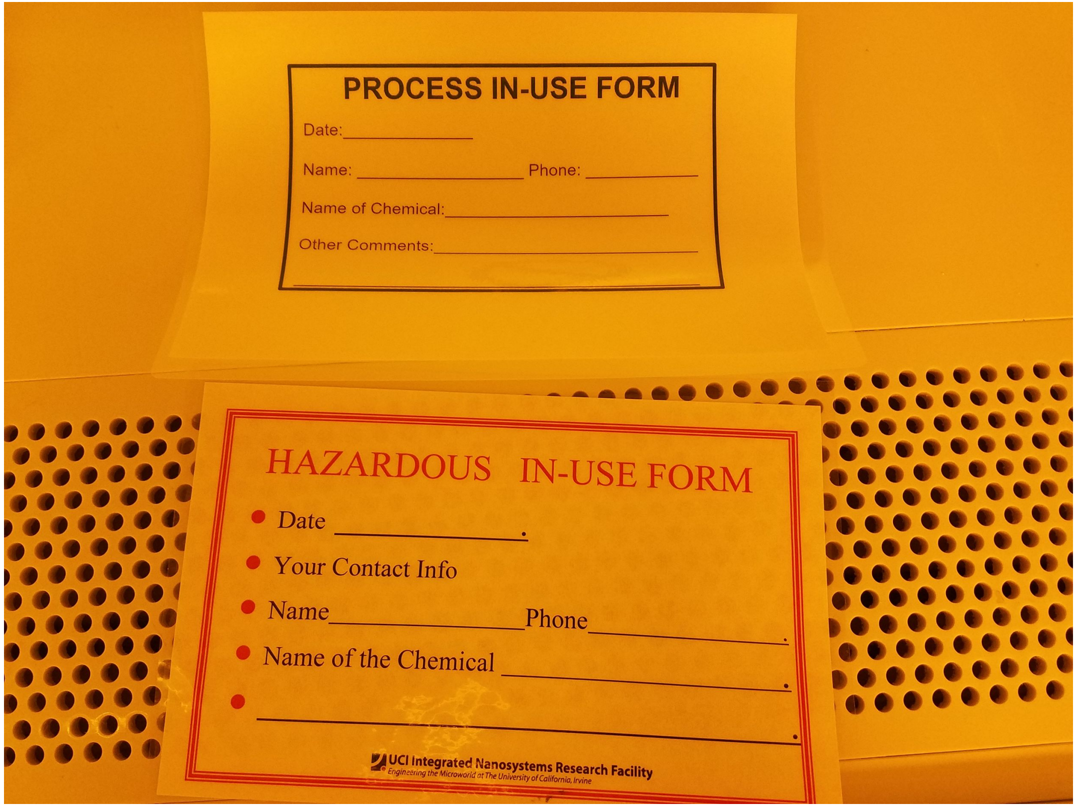
- Hot Plates unattended and/or in forbidden areas

- Illegible/Incomplete process in progress and hazardous in use forms



PROCESS IN-USE FORM

Date:____________

Name: ________________ Phone: __________

Name of Chemical:____________________

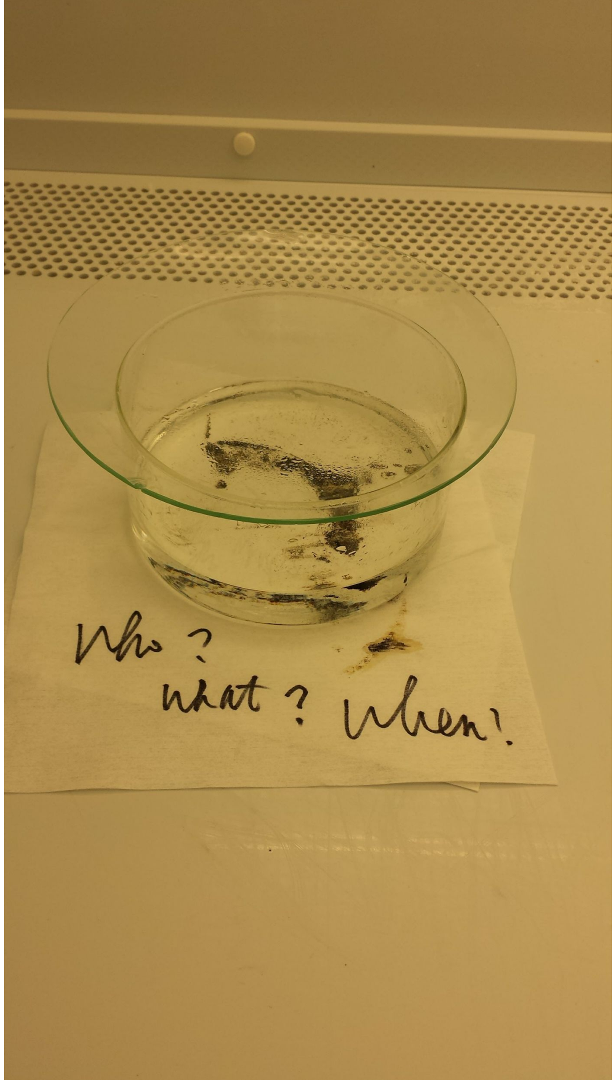
Other Comments:______________________

____

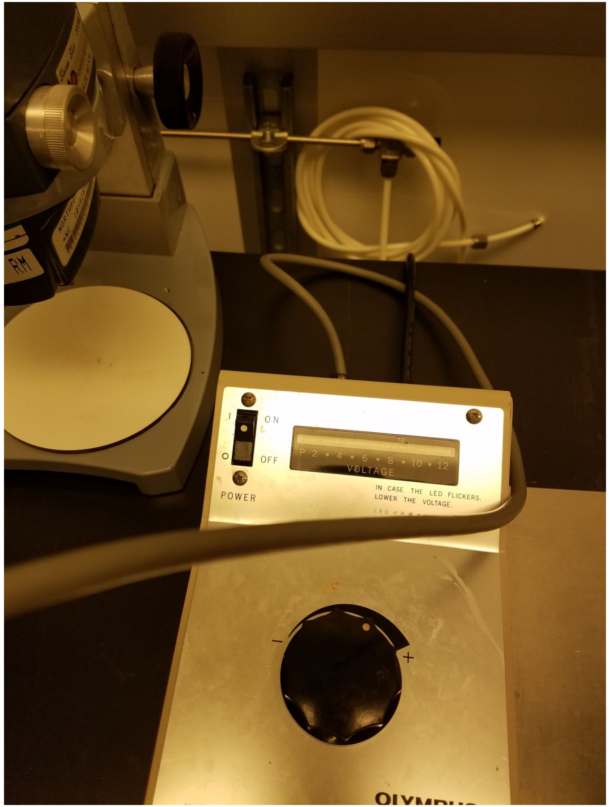
HAZARDOUS IN-USE FORM

- Date _________________.
- Your Contact Info
- Name________________Phone_______________.
- Name of the Chemical ___________________.
- ______________________________________.

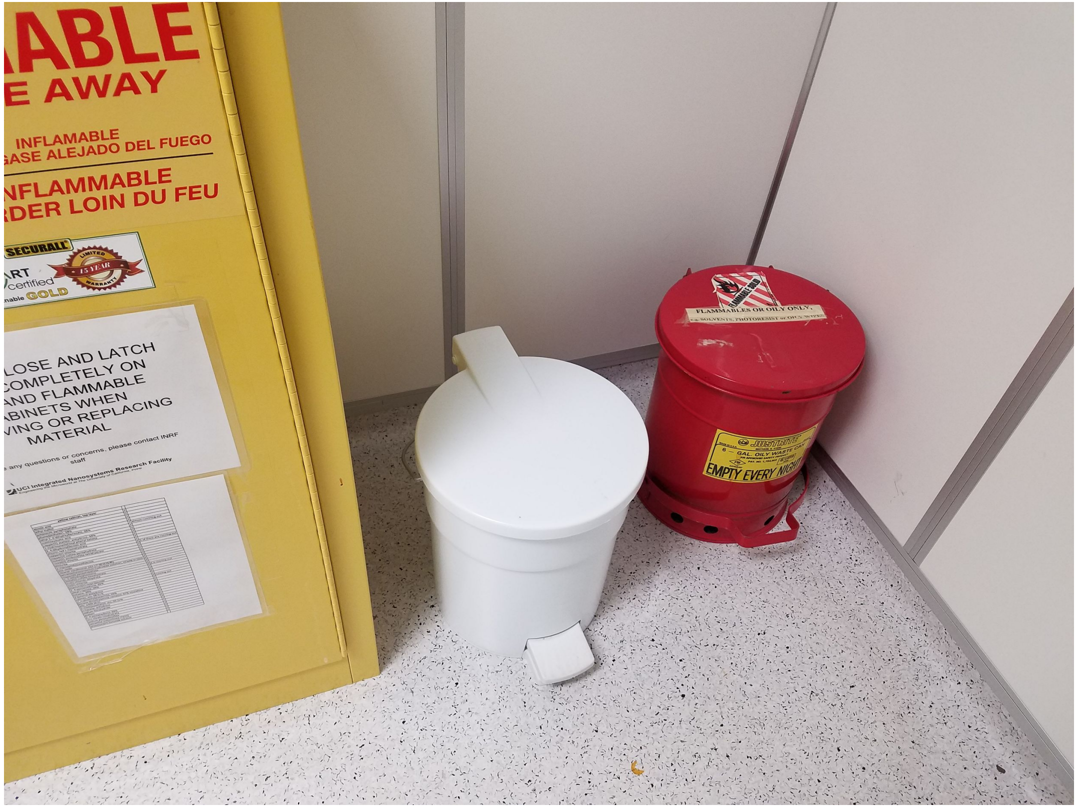
UCI Integrated Nanosystems Research Facility
Engineering the Microworld at The University of California, Irvine


Who?
what? When!

- Microscopes left on



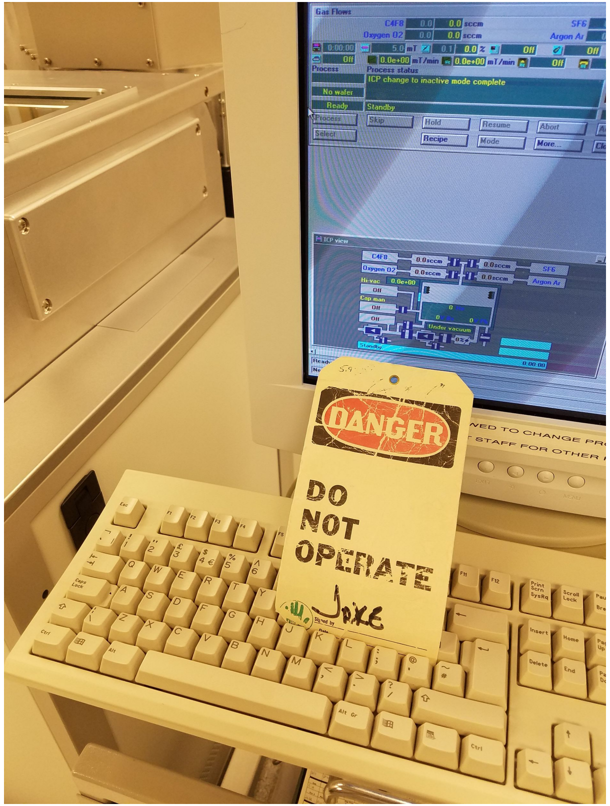
- Trash left in the wrong trash bin

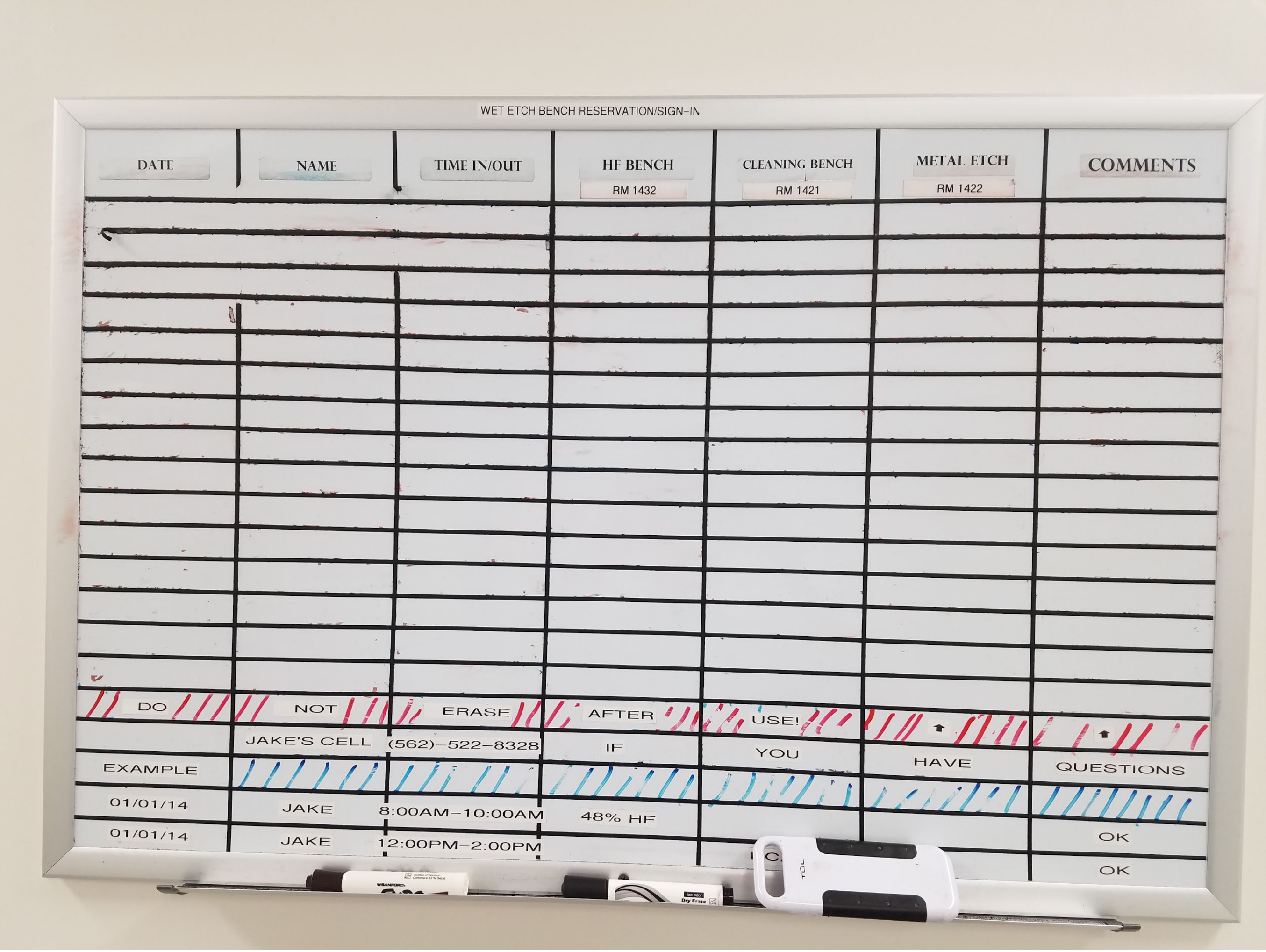


- Chemical bottles improperly stored

- Oven doors not closed properly, forbidden items found inside

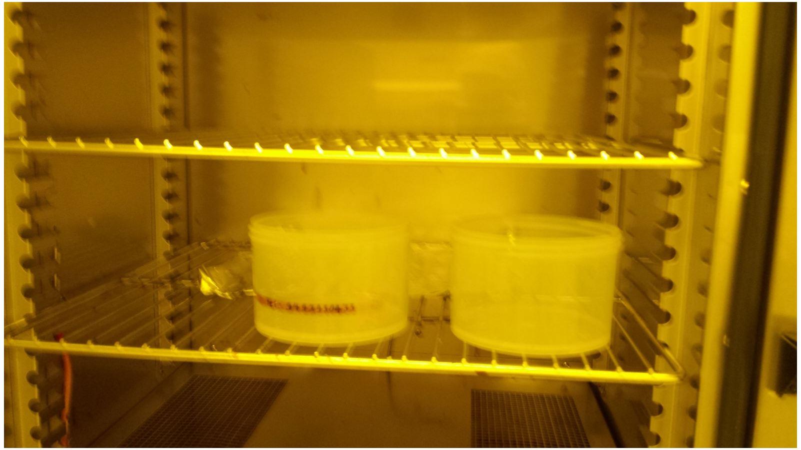
- Lock Out / Tag Out tags not respected





WET ETCH BENCH RESERVATION/SIGN-IN

DATE	NAME	TIME IN/OUT	HF BENCH RM 1432	CLEANING BENCH RM 1421	METAL ETCH RM 1422	COMMENTS
DO	NOT	ERASE	AFTER	USE!	⬆	⬆
	JAKE'S CELL	(562)-522-8328	IF	YOU	HAVE	QUESTIONS
EXAMPLE						
01/01/14	JAKE	8:00AM-10:00AM	48% HF			OK
01/01/14	JAKE	12:00PM-2:00PM		C.		OK




CENTER
EUROTHERM
0.0
3.2
EUROTHERM
31
968
EUROTHERM
-0.1
4.0
OP1
OP2
A/M
PAR
HOLD
RUN
DIGITROL
BY MRL
EXCESS TEMPERATURE
TUBE NO. 2
ELEMENT POWER ON
OFF
CONTROL
EXCESS TEMP
TEMP RESET
ELEMENT POWER ON


P2
Bake Oven
DOWN
Ultra-Clean "100"
PROCESS : DEHYDRATION BAKE
TEMPERATURE : PRESET TO 120°C
Imperial IV
MICROPROCESSOR OVEN
P1
Bake Ove
UP
Imperial

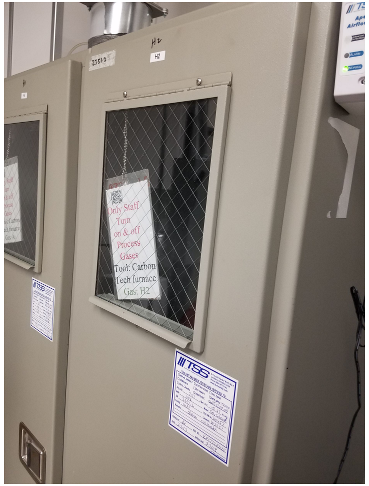

BLOWER
AIRFLOW CONTROL
PLEASE C
RESIST SPINNE
WORKING HEIGHT
FULL PERSONNEL PROTECTION PROVIDED AT THIS OPENING
VAC
N2
Shipley a


LIGHT
ON
OFF
BLOWER
AIRFLOW CONTROL
PL
WORKING HEIGHT
FULL PERSONNEL PROTECTION PROVIDED AT THIS OPENING
VAC
N2
Shi

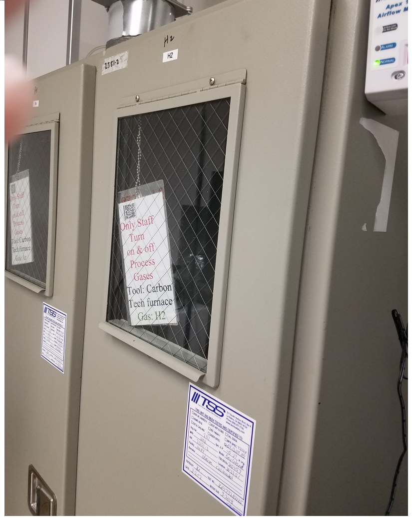

AIRFLOW CONTROL
FULL PERSONNEL PROTECTION PROVIDED AT THIS OPENING
VAC
N2

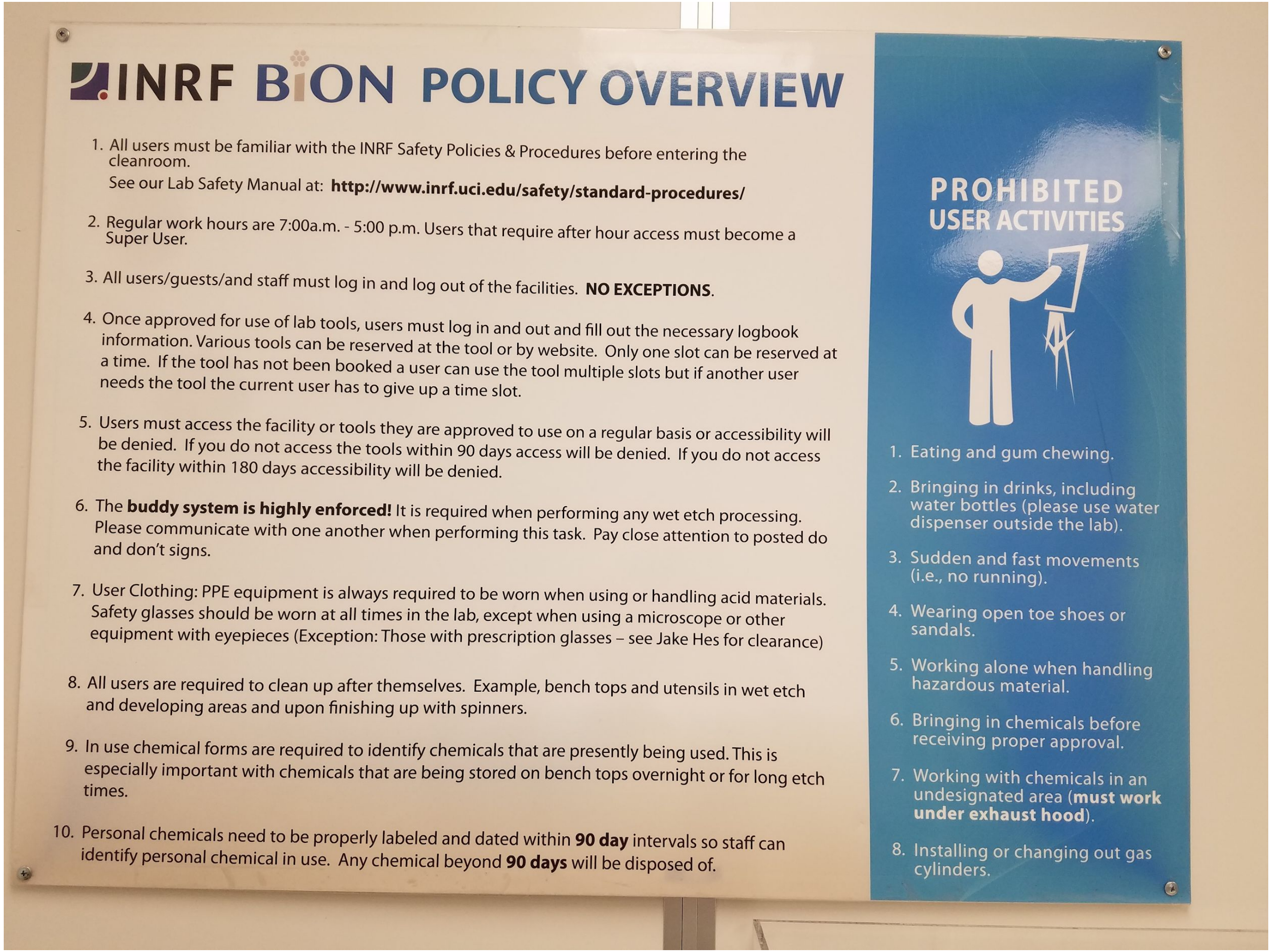

PLEASE CLEAN UP
RESIST SPINNER AFTER USE
THANKS
JAKE AND STAFF
UCI Integrated Nanosystems Research Facility
This wet bench is dedicated for
PHOTORESIST
PROCE
toresist
Sure to clean spinner after each use
If questions or concerns, please contact INRF staff at X4-8239
Integrated Nanosystems Research Facility
RUN STOP
VACUUM
ENTER
F1


Only Staff Turn on & off Process Gases
Tool: BMR PECVD
Gas: Ar


H2
Only Staff Turn on & off Process Gases
Tool: Carbon Tech furnace
Gas: H2
TSS


IN USE


H2
Only Staff Turn on & off Process Gases
Tool: Carbon Tech furnace
Gas: H2
TSS

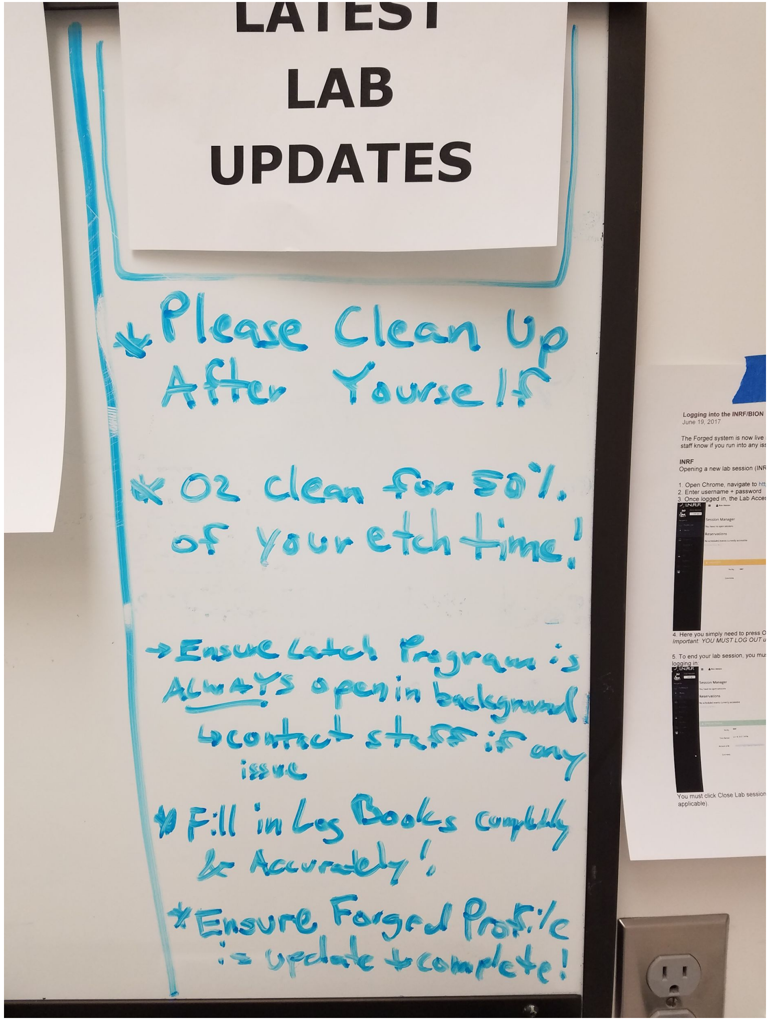


INRF BiON POLICY OVERVIEW

1. All users must be familiar with the INRF Safety Policies & Procedures before entering the cleanroom.
   See our Lab Safety Manual at: **http://www.inrf.uci.edu/safety/standard-procedures/**
2. Regular work hours are 7:00a.m. - 5:00 p.m. Users that require after hour access must become a Super User.
3. All users/guests/and staff must log in and log out of the facilities. **NO EXCEPTIONS**.
4. Once approved for use of lab tools, users must log in and out and fill out the necessary logbook information. Various tools can be reserved at the tool or by website. Only one slot can be reserved at a time. If the tool has not been booked a user can use the tool multiple slots but if another user needs the tool the current user has to give up a time slot.
5. Users must access the facility or tools they are approved to use on a regular basis or accessibility will be denied. If you do not access the tools within 90 days access will be denied. If you do not access the facility within 180 days accessibility will be denied.
6. The **buddy system is highly enforced!** It is required when performing any wet etch processing. Please communicate with one another when performing this task. Pay close attention to posted do and don't signs.
7. User Clothing: PPE equipment is always required to be worn when using or handling acid materials. Safety glasses should be worn at all times in the lab, except when using a microscope or other equipment with eyepieces (Exception: Those with prescription glasses – see Jake Hes for clearance)
8. All users are required to clean up after themselves. Example, bench tops and utensils in wet etch and developing areas and upon finishing up with spinners.
9. In use chemical forms are required to identify chemicals that are presently being used. This is especially important with chemicals that are being stored on bench tops overnight or for long etch times.
10. Personal chemicals need to be properly labeled and dated within **90 day** intervals so staff can identify personal chemical in use. Any chemical beyond **90 days** will be disposed of.

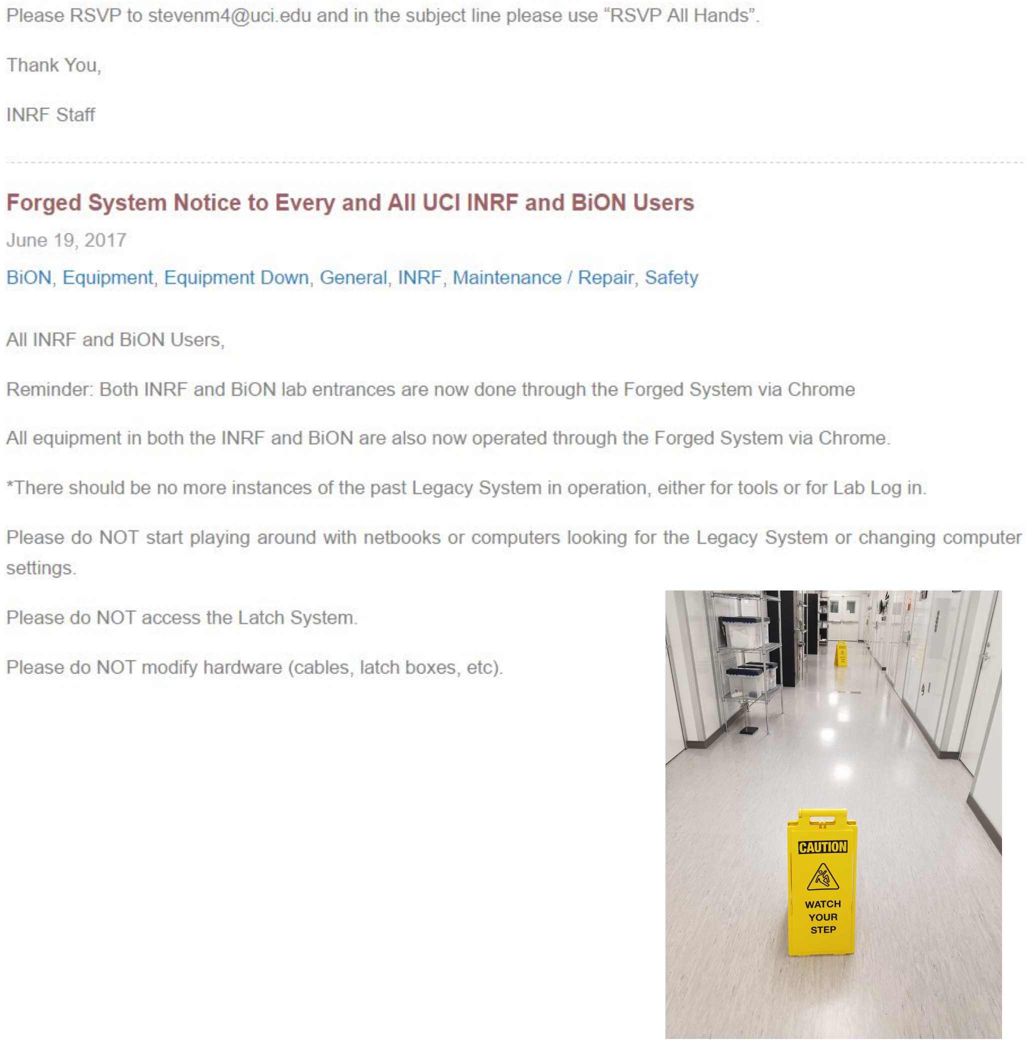
PROHIBITED USER ACTIVITIES

1. Eating and gum chewing.
2. Bringing in drinks, including water bottles (please use water dispenser outside the lab).
3. Sudden and fast movements (i.e., no running).
4. Wearing open toe shoes or sandals.
5. Working alone when handling hazardous material.
6. Bringing in chemicals before receiving proper approval.
7. Working with chemicals in an undesignated area (**must work under exhaust hood**).
8. Installing or changing out gas cylinders.



LATEST LAB UPDATES

- Please Clean Up After Yourself
- O2 clean for 50% of your etch time!
- → Ensure Latch Program is ALWAYS open in background
  - ↳ contact staff if any issue
- Fill in Log Books completely & Accurately!
- Ensure Forged Profile is update & complete!



Please RSVP to stevenm4@uci.edu and in the subject line please use “RSVP All Hands”.

Thank You,

INRF Staff

Forged System Notice to Every and All UCI INRF and BiON Users

June 19, 2017

BiON, Equipment, Equipment Down, General, INRF, Maintenance / Repair, Safety

All INRF and BiON Users,

Reminder: Both INRF and BiON lab entrances are now done through the Forged System via Chrome

All equipment in both the INRF and BiON are also now operated through the Forged System via Chrome.

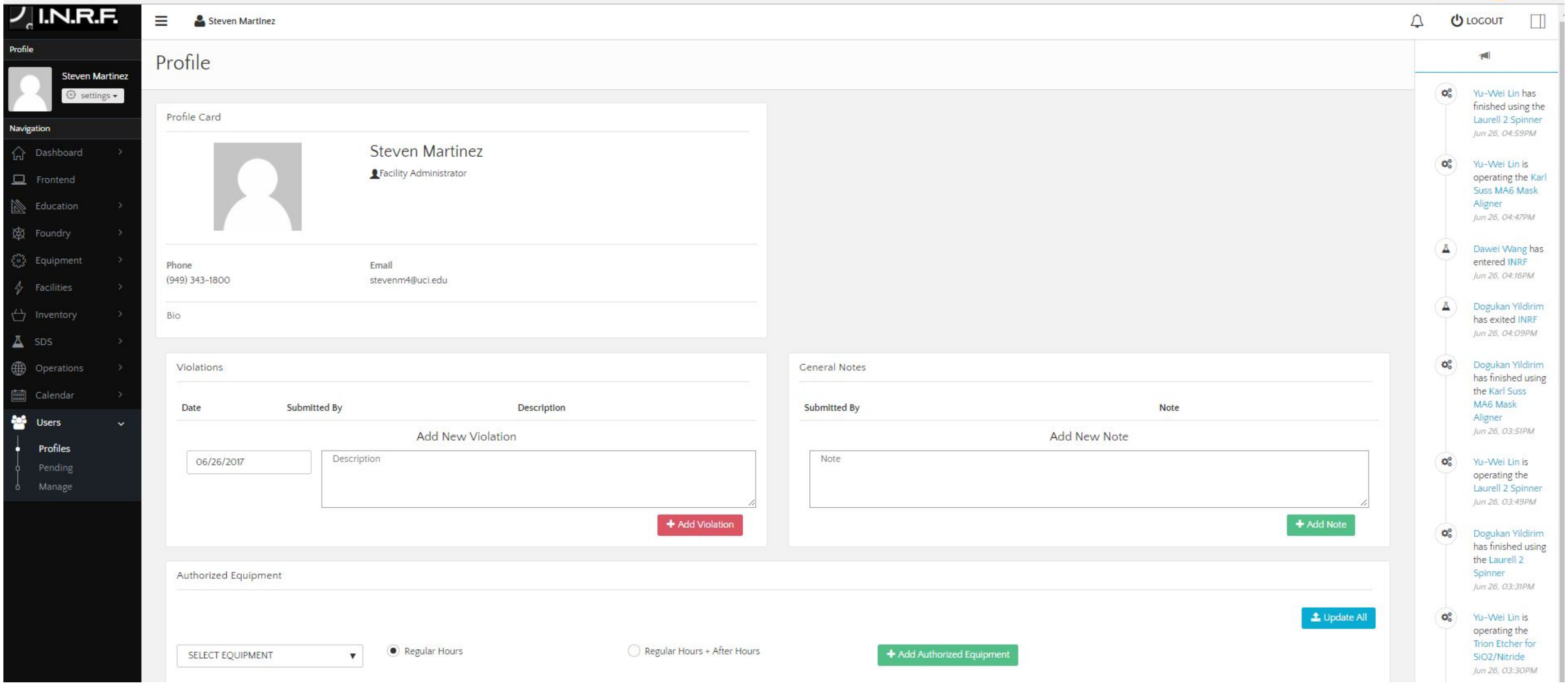
*There should be no more instances of the past Legacy System in operation, either for tools or for Lab Log in.

Please do NOT start playing around with netbooks or computers looking for the Legacy System or changing computer settings.

Please do NOT access the Latch System.

Please do NOT modify hardware (cables, latch boxes, etc).

Forged Violations Page



Profile Card

Steven Martinez

Facility Administrator

Phone
(949) 343-1800

Email
stevenm4@uci.edu

Bio

Violations

Date	Submitted By	Description

Add New Violation

06/26/2017

Description

General Notes

Submitted By	Note

Add New Note

Note

Authorized Equipment

SELECT EQUIPMENT ▾ ● Regular Hours ○ Regular Hours + After Hours

Yu-Wei Lin has finished using the Laurell 2 Spinner
Jun 26, 04:59PM

Yu-Wei Lin is operating the Karl Suss MA6 Mask Aligner
Jun 26, 04:47PM

Dawei Wang has entered INRF
Jun 26, 04:16PM

Dogukan Yildirim has exited INRF
Jun 26, 04:09PM

Dogukan Yildirim has finished using the Karl Suss MA6 Mask Aligner
Jun 26, 03:51PM

Yu-Wei Lin is operating the Laurell 2 Spinner
Jun 26, 03:49PM

Dogukan Yildirim has finished using the Laurell 2 Spinner
Jun 26, 03:31PM

Yu-Wei Lin is operating the Trion Etcher for SiO2/Nitride
Jun 26, 03:30PM